

Sapphire Detectors

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collaboration

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Sapphire properties

Density	3.98 g cm⁻³	3.52 g cm^{-3}
Dielectric constant	t 9.3 - 11.5	5.7
Breakdown field	~10 6 V cm $^{-1}$ *	107 V cm ⁻¹
Resistivity	>10¹ ⁴ Ω cm	>10¹¹ Ω cm
Band gap	9.9 eV	5.45 eV
Electron mobility 🔬	~600 (20°C) **	$1800 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$
Hole mobility	30000 (40ºK) **	$1200 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$
Average signal crea	ated 22 eh µm	1 ⁻¹ 36 eh µm ⁻¹

(Diamond)

* Typical operation field ~10⁴ V cm⁻¹

**Optical-Pump/THz-Probe Spectroscopy

Synthesis of sapphire (Al₂O₃)

- Single crystals are grown by Czochralski process
- Growing speed ~100 mm/hour
- Up to 440 mm diameter crystals
- Crystal weight up to ~500 Kg
- World annual production >250 tons
- Used in chemistry, electronics, semiconductor industry, lasers, etc.



Impurity	Na	Si	Fe	Ca	Mg	Ni	Ti	Mn	Cu	Zr	Y
ppm	8	2	5	5	1	<3	<1	3	<3	2	2

Sapphire charge collection efficiency Measured at ⁹⁰Sr setup SC Sapphire Sapphire charge collection efficiency 10x10x0.5 mm³ 10 CCE, percent **Metallization** 8 Al+Ti+Au 6 Signal ~ 600 e⁻ ³⁰Sr 4 -HV c 2 500 μm sample, MIP signal 0 -2 200 400 600 800 1000 0

Bias, V

6 December 2013

Irradiation of sapphire and diamond sensors at 10 MeV electron beam





10 MGy ~ $5 \cdot 10^{16}$ MIPs ~ $2.5 \cdot 10^{15}$ [1 MeV neq] (NIEL, G.P.Summers)

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Detection of MIPs











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Test beam at DESY 08.2013



• 5 GeV electrons + pixel telescope



Test beam at DESY. EUDET telescope





Detector support platform at XY-table

Test beam at DESY. Detector installed



Telescope information only, XY of vertices



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Sapphire detector signal, 500 V bias DUT information only



Sapphire detector signal, 500 V bias DUT information only



Sapphire detector signal vs bias voltage





















Conclusions and outlook

- Sapphire (single crystal Al₂O₃) is a very promising wide-bandgap material for HEP applications
- Produced in large quantities for industrial purposes, large size wafers are available (~25 cm, up to 40 cm diameter is possible), not expensive
- Perfect electrical properties, excellent radiation hardness, but presently low charge collection efficiency (~ 5%, probably due to high level of impurities)
- For many applications, where radiation hardness is an issue (large particle fluxes), sapphire could be used as it is, i.e. leakage current sensors, detection of particle bunches, calorimetry etc
- Sapphire sensors are successfully operating at FLASH, are to be installed at FLASH-2 and XFEL
- Sapphire sensors could be used for MIP detection in cases where tracker material budget is not critical (beam diagnostics, very forward tracking)
- Sapphire detector designed for MIP detection was tested at the DESY test beam. Preliminary results show expected performance.
- Further developments will follow.



Thank you!

Optical-pump/THz-Probe Spectroscopy

40 - 350 K⁰ F.Wang et.al., 2004

Ultrafast photo-excitation + THz time-domain spectroscopy







Irradiation of sapphire and diamond sensors at 10 MeV electron beam



Leakage current after irradiation is still at few pA level

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Test of sapphire and quartz sensors at the 10 MeV electron beam



Other two samples. Some recovery effect for sapphire during beam interruptions.



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